



Attorney Docket No. H1559

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re patent application of

Applicant: Pawloski et al.
Serial No.: 10/790,457
Filed: March 1, 2004
For: METHOD FOR REMOVAL OF IMMERSION LITHOGRAPHY MEDIUM IN IMMERSION LITHOGRAPHY PROCESSES
Art Unit: Not yet known
Examiner: Not yet known

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1345

Sir:

1. Pursuant to 37 C.F.R. 1.97 and 1.98, and in compliance with 37 C.F.R. 1.56, the Office's attention is directed to the patents, pending applications, publications and other information listed on the attached PTO-1449. A copy of each listed document is enclosed except for: (a) pending applications or (b) those previously cited or submitted to the Office in the following application(s) upon which this application relies for an earlier filing date under 35 U.S.C. 120:

Serial No.: _____
Filing Date: _____

Regarding any document, publication or other information for which a date is not given on the attached PTO-1449, Applicant(s) believe(s) the same may qualify as "prior" art to this application and should be treated accordingly, although Applicant(s) reserve(s) the right to contest the prior art status of any document, publication or information, should issue arise.

2. Regarding each listed document that is not in the English language, an English-language translation accompanies this Statement as indicated on the attached PTO-1449 or a concise explanation of the relevance of the document is set forth in the following document(s):

- (a) ____ Copy of each English language version of a search report indicating the degree of relevance found by the foreign office of each document being submitted from the search report.
- (b) ____ Attachment entitled "Concise Explanation of Relevance of Non-English Language Documents".

3. Pursuant to 37 C.F.R. 1.97(b) this Statement is being filed (one must be checked):

- (a) X Within 3 months of the filing date, date of entry into the National Stage, or filing date of CPA.
- (b) ____ Before the mailing date of a first Office Action on the merits. If this Statement is not filed before the mailing date of a first Office Action on the merits, the required certification is given below or, in the absence thereof, the Office is authorized to charge the required fee set forth in 37 C.F.R. 1.17(p) to Deposit Account No. 18-0988 for consideration of this Statement.
- (c) ____ Before the mailing date of a first Office Action on the merits after a first or second submission after final rejection under 37 C.F.R. 1.129(a).

(d) ___ After the period set forth in 37 C.F.R. 1.97(b) but before the mailing date of either a final action or a notice of allowance.

(1) ___ The required certification is given below, or

(2) ___ Enclosed is a check covering the fee set forth in 37 C.F.R. 1.17(p) for consideration of this Statement, or

(3) ___ Charge the fee set forth in 37 C.F.R. 1.17(p) to Deposit Account No. 18-0988

(e) ___ After the mailing date of either a final action or a notice of allowance, but before payment of the issue fee. Petition hereby is made for consideration of this Statement and the required certification is indicated below.

(1) ___ Enclosed is a check covering the fee set forth in 37 C.F.R. 1.17(p), or

(2) ___ Charge the fee set forth in 37 C.F.R. 1.17(p) to Deposit Account No. 18-0988.

4. Certification (if applicable)

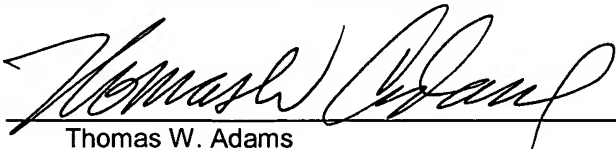
(a) ___ The undersigned hereby certifies that each item of information contained in this Statement was first cited in any communication from a foreign patent office in a counterpart foreign application not more than 3 months prior to the filing of this Statement.

(b) ___ The undersigned hereby certifies that no item of information contained in this Statement was cited in a communication from a foreign patent office in a counterpart foreign application or, to the undersigned's knowledge after making reasonable inquiry, was known to any individual designated in 37 C.F.R. 1.56(c) more than 3 months prior to the filing of this Statement.

5. The Commissioner is hereby authorized to charge any additional fees or credit any overpayment to Deposit Account No. 18-0988.

Respectfully Submitted,

RENNER, OTTO, BOISSELLE & SKLAR, LLP

By 
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CERTIFICATE OF MAILING UNDER 37 C.F.R. §1.8

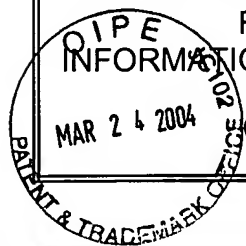
I hereby certify that this correspondence (along with any paper referenced as being attached or enclosed) is being deposited on the below date with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to Commissioner for Patents, U.S. Patent and Trademark Office, Washington, D.C. 20231.

Date: 03/22/04


Janet Farr

Form PTO-1449 (Modified)	Atty Docket No.	Serial No.
	H1559	10/790,457
	Applicant: Pawloski	
LIST OF PATENTS AND PUBLICATIONS FOR APPLICANT'S INFORMATION DISCLOSURE STATEMENT	Filing Date	Group
	03/01/04	

(Use several sheets if necessary)



U.S. PATENT DOCUMENTS

Examiner Initial	Document Number	Date	Name	Class	Sub-class	Filing Date if Appropriate
	5,610,683	03/11/97	Takahashi	355	53	
	5,900,354	05/04/99	Batchelder	430	395	
	6,024,801	02/15/00	Wallace et al.	134	1	
	6,602,349 B1	08/05/03	Chandra et al.	134	19	
	6,612,317 B2	09/02/03	Costantini et al.	134	58	
	2002/0163629 A1	11/07/02	Switkes et al.	355	53	
	2003/0064604 A1	04/03/03	Umeda	438	745	
	2003/0123040 A1	07/03/03	Almogy	355	69	
	2003/0174408 A1	09/18/03	Rostalski et al.	359	642	

FOREIGN PATENT DOCUMENTS

Examiner Initial	Document Number	Date	Country	Class	Sub-class	Translation	
						Yes	No
	0 822 583 A2	04/02/98	EP				
	0 829 312 B1	04/06/03	EP				

OTHER ART

Examiner Initial	Author, Title, Date, Pertinent Pages, etc.
	Switkes et al.; "Immersion Lithography at 157 nm"; J. Vac. Sci. Technol. B 19(6), Nov./Dec. 2001; pp. 2353-2356.
	Smith et al.; "Immersion Optical Lithography at 193 nm"; Rochester Institute of Technology; Future Fab Int'l, Vol. 15 (07/11/2003).
	Goldfarb et al.; "Aqueous-based Photoresist Drying Using Supercritical Carbon Dioxide to Prevent Pattern Collapse"; J. Vac. Sci. Technol. B 18(6), Nov./Dec. 2000; pp. 3313-3317.
	Jincao et al.; "Prevention of Photoresist Pattern Collapse by Using Liquid Carbon Dioxide"; Ind. Eng. Chem. Res. 2001, 40, pp. 5858-5860.
	Sundararajan et al.; "Supercritical CO ₂ Processing for Submicron Imaging of Fluoropolymers"; Chem. Mater, 2000, 12, pp. 41-48.

EXAMINER	DATE CONSIDERED
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EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

Information Disclosure Statement PTO-1449 (Modified)

The identification of any reference is not intended to be, and should not be understood as being, an admission that such publication, in fact, constitutes "prior art" within the meaning of applicable law since, for example, a given reference may have a later effective date than first seems apparent or the reference may have an effective date which can be antedated. The "prior art" status of any reference is a matter to be resolved during prosecution.

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